

CHEMICAL VAPOR DEPOSITION SYSTEM, ARRANGEMENT OF CHEMICAL VAPOR DEPOSITION SYSTEMS, AND CHEMICAL VAPOR DEPOSITION METHOD

ABSTRACT

A chemical vapor deposition system, method and arrangement of systems are disclosed. The system includes a coating chamber, a fluid introduction system, and an arrangement of radiant heating elements. The coating chamber has an enclosing border extending around a coating region and an access portion positioned in an axial orientation relative to the enclosing border, the coating chamber being in a fixed and horizontal position. The fluid introduction system includes a vacuum pump and a fluid introduction arrangement arranged and disposed to introduce a fluid to the coating chamber for chemical vapor deposition coating of an article in the coating chamber. The arrangement of radiant heating elements is positioned outside of the coating chamber and is thermally connected with the enclosing border of the coating chamber to heat zones within the coating chamber. The method uses the system. The arrangement includes more than one of the chemical vapor deposition systems.

Fig. 4